

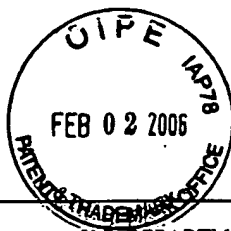
Sheet 1 of 2

Form PTO-1449 (Substitute)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Attorney Docket Number TEGL-01168US0	Application/Patent Number 10/636,020
			Applicant/Patent Owner Tue Nguyen	
			Filing/Issue Date August 7, 2003	Group Art Unit 1734

Information Disclosure Statement
 BY APPLICANT
 (Use several sheets if necessary)

U.S. PATENTS

Examiner Initial	Patent Number	Issue Date	Inventor(s)	Class	Subclass	Filing Date
	3,514,391	05/1970	Hablanian <i>et al.</i>			
	5,804,046	09/1998	Sawada <i>et al.</i>			
	5,837,057	11/1998	Koyama <i>et al.</i>			
	4,033,287	07/1977	Alexander, Jr. <i>et al.</i>			
	5,277,751	01/1994	Ogle			
	5,417,798	05/1995	Nishibayashi <i>et al.</i>			
	5,445,709	08/1995	Kojima <i>et al.</i>			
	5,503,725	04/1996	Sablev <i>et al.</i>			
	5,800,619	09/1998	Holland <i>et al.</i>			
	5,814,154	09/1998	Boitnott <i>et al.</i>			
	5,846,331	12/1998	Miyamoto			
	5,874,704	02/1999	Gates			
	5,968,275	10/1999	Lee <i>et al.</i>			
	5,922,223	07/1999	Okumura <i>et al.</i>			
	5,993,594	11/1999	Wicker <i>et al.</i>			
	6,006,694	12/1999	DeOrnellas <i>et al.</i>			
	6,026,764	02/2000	Hwang			
Examiner <i>JR</i>	Date Considered <i>2/06</i>					



Form PTO-1449 (Substitute)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	Attorney Docket Number TEGL-01168US0	Application/Patent Number 10/636,020
Information Disclosure Statement BY APPLICANT (Use several sheets if necessary)		Applicant/Patent Owner Tue Nguyen	
		Filing/Issue Date August 7, 2003	Group Art Unit 1734
U.S. PATENTS			
	6,046,425	04/2000	Kaji et al.
	6,050,217	04/2000	Li
	6,059,922	05/2000	Yamazaki et al.
	6,067,930	05/2000	Minato et al.
	6,170,431	01/09/01	DeOrnellas et al.
	6,173,674	01/2001	DeOrnellas et al.
OTHER DOCUMENTS (Include author (if any), title, publisher and place of publication, date and pertinent pages)			
	International Search Report for PCT/US98/25437, mailed Mar. 19, 1999.		
	Reinberg, <i>Plasma Etch Equipment Technology</i> , M. Triodes, Perkin-Elmer Corporation, Norwalk, CT, 1989 by Academic Press, Inc. ISBN 0-12-469370-9; pp. 350-351.		
	Plasma Etching Technology, Feb. 10-11, 1997, Burlingame, CA, Continuing Education in Engineering University Extension. U. of California, Berkeley, <i>Plasma Etching Technology, An Overview</i> , D.L. Flamm, D.L. Flamm 1992-1996, title 95011501v2, D.L. Flamm 1995, src5012608, 3 pgs.		
Examiner <i>Jen</i>		Date Considered <i>2/06</i>	
*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.			
*1 = Copy not submitted because it was submitted in prior application SN __/____, filed _____, 20____, relied on under 35 USC §120.			
**2 = Copy not submitted because it was submitted in prior application SN __/____, filed _____, 20____, relied on under 35 USC §120.			